

Form 1449*	Atty. Docket No.: 303.676US3	Serial No. Unknown
	Applicant: Gurtej Singh Sandhu et al.	
	Filing Date: Herewith	Group: Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	PRO 08/28/01 089/94123	

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**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	4,340,617	07/20/1982	Deutsch, et al.	427	53.1	05/19/80
	4,343,870	08/10/1982	Heller, A., et al.	429	111	09/08/80
	4,359,490	11/16/1982	Lehrer, W.I.	427	95	07/13/81
	4,713,258	12/15/1987	Umemura	427	35	07/03/85
	4,721,631	01/26/1988	Endo, et al.	427	66	03/09/87
	4,751,101	06/14/1988	Joshi, R.V.	427	39	04/30/87
	4,868,005	09/19/1989	Ehrlich, et al.	427	53.1	03/10/88
	4,876,112	10/24/1989	Kaito, et al.	427	38	03/27/87
	4,884,123	11/28/1989	Dixit, P., et al.	357	71	02/19/87
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	4,957,777	09/18/1990	Ilderem, V., et al.	427	55	10/12/89
	4,971,655	11/20/1990	Stefano, et al.	156	659.1	12/26/89
	5,005,519	04/01/1991	Egermeier, et al.	118	722	03/14/90
	5,015,330	05/14/1991	Okumura, K., et al.	156	643	02/28/90
	5,022,905	06/11/1991	Grundy, et al.	65	60.51	10/12/89
	5,032,233	07/16/1991	Yu, C., et al.	204	192.28	09/05/90
	5,049,975	09/17/1991	Ajika, N., et al.	357	71	03/12/90
	5,124,780	06/23/1992	Sandhu, G.S., et al.	357	67	06/10/91
	5,136,362	08/04/1992	Grief, et al.	357	67	11/27/90
	5,147,819	09/15/1992	Yu, C., et al.	437	173	02/21/91
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	5,202,579	04/13/1993	Fujii, H., et al.	257	751	01/21/92
	5,227,331	07/13/1993	Westmoreland, D.	437	174	02/10/92
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	5,246,881	09/21/1993	Sandhu, G.S., et al.	437	192	04/14/93
	5,252,518	10/12/1993	Sandhu, et al.	437	200	03/03/92
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	5,258,096	11/02/1993	Sandhu, et al.	156	643	08/20/92
	5,273,783	12/28/1993	Wanner	427	250	03/24/93
	5,275,715	01/04/1994	Tuttle	205	123	01/23/92
	5,278,100	01/11/1994	Doan, T.T., et al.	437	200	11/08/91
	5,306,951	04/26/1994	Lee, et al.	257	755	05/14/92
	5,320,880	06/14/1994	Sandhu, G.S., et al.	427	578	11/18/93
	5,341,016	08/23/1994	Prall, K.D., et al.	257	412	06/16/93
	5,344,792	09/06/1994	Sandhu, G.S., et al.	437	200	03/04/93
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	5,384,284	01/24/1995	Doan, T.T., et al.	437	190	10/01/93
	5,384,289	01/24/1995	Westmoreland, D.L.	437	245	06/17/93
	5,391,410	02/21/1995	Nii, T., et al.	427	578	05/28/93
	5,393,564	02/28/1995	Westmoreland, et al.	427	248.1	05/02/94
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	5,453,640	09/26/1995	Kinoshita, Y.	257	520	12/20/94
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	98/34445	08/06/1998	PCT	H05K	3/26		

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				Class	Subclass

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